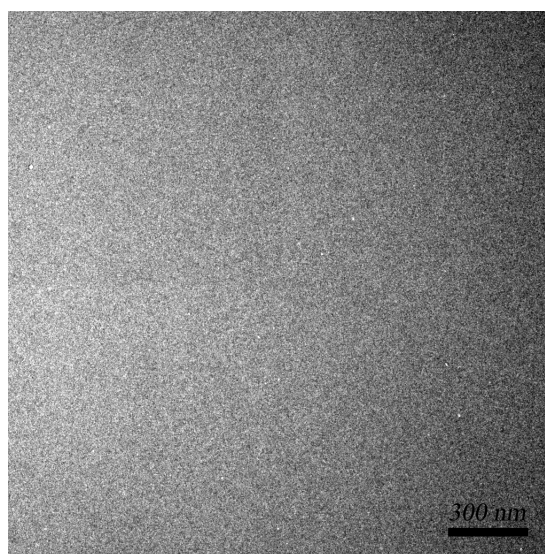


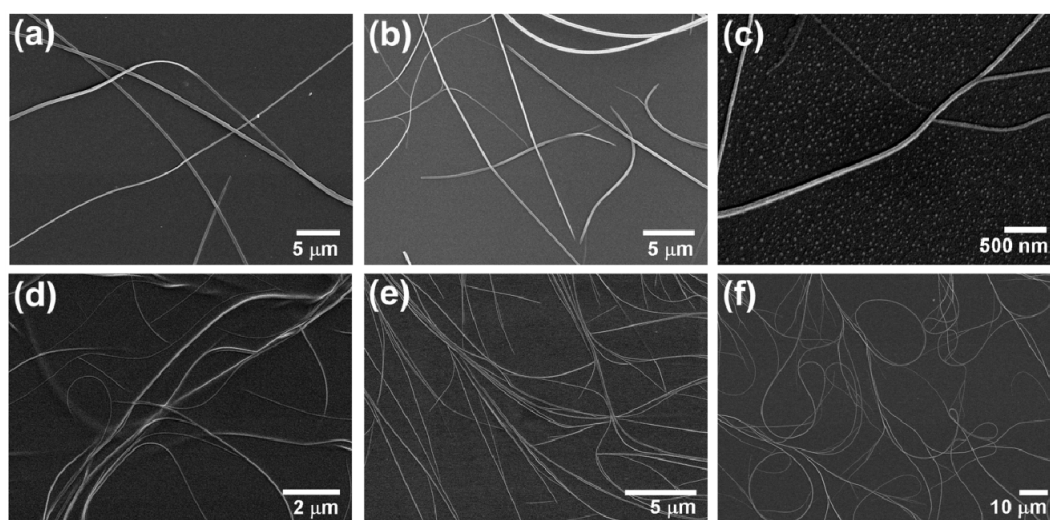
**Selected-Area In Situ Generation of Highly Fluorescent Organic Nanowires  
Embedded in a Polymer Film: The Solvent-Vapor-Induced Self-Assembly  
Process**

Jong Won Chung<sup>a</sup>, Byeong-Kwan An<sup>b</sup>, Fumio Hirato<sup>c</sup>, Jong H. Kim<sup>a</sup>, Hiroshi Jinnai<sup>c</sup>, *and* Soo Young Park<sup>\*a</sup>

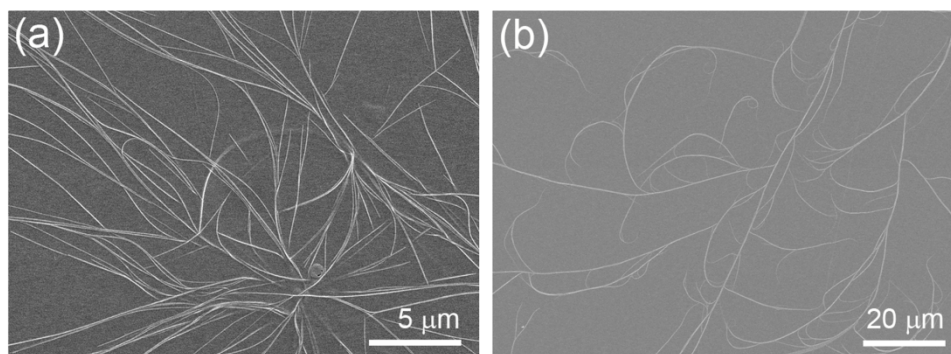
**ELECTRONIC SUPPLEMENTARY INFORMATION**



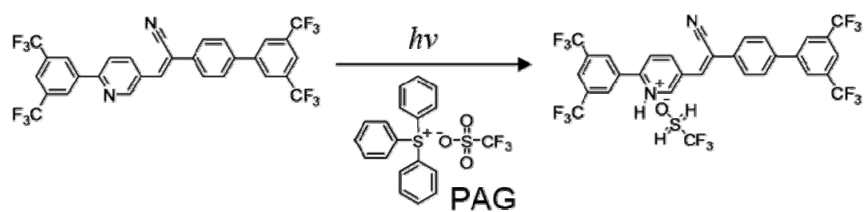
**Fig. S1** TEM image of CN-TFMBE-doped polystyrene matrix before SVA.



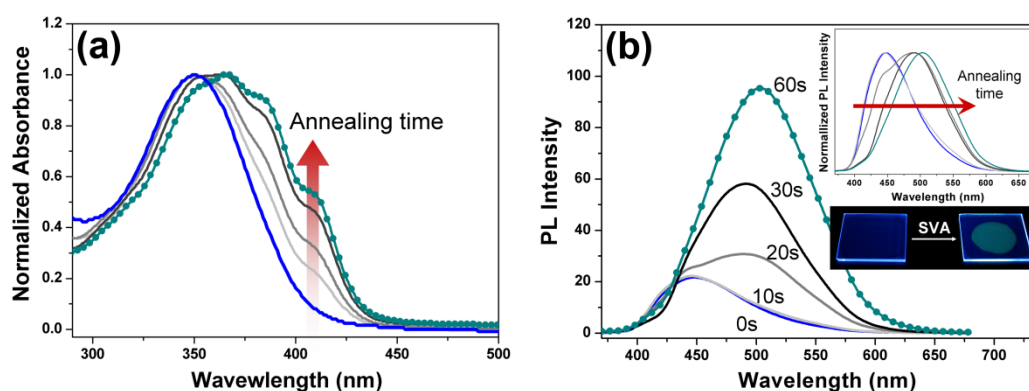
**Fig. S2** Self-assembled 1D nanowire structures of CN-TFMBE generated by solvent-vapor annealing on various polymer matrices and solid substrates: (a) polystyrene (PS), (b) regio-regular poly(3-hexylthiophene) (RR-P3HT) and (c) poly(9-vinylcarbazole) (PVK) on a glass substrate; CN-TFMBE 1D nanowires fabricated on (d) a PMMA coated glass substrate, (e) a silicon substrate, and (f) a mica substrate.



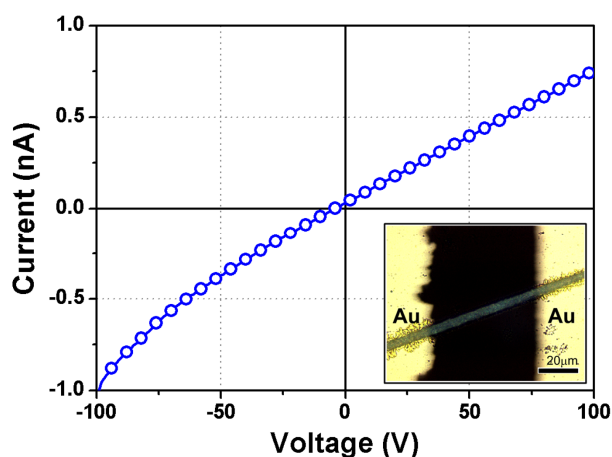
**Fig. S3** Self-assembled 1D nanowire structures of Py-CN-TFMBE/PMMA film generated by the solvent-vapor annealing process on two substrates: (a) silicon substrate and (b) mica substrate.



**Scheme S1** Photochemical reaction of Py-CN-TFMBE by photo-acid generator.



**Fig. S4** UV-visible absorption spectra and PL spectra of a Py-CN-TFMBE doped-PMMA film after nanoaggregate formation. (a) Normalized UV-visible absorption spectra and (b) PL spectra for different vapor-exposure times, before (blue line) and after (greenish-blue dotted line) nanowire formation. Insets show an image of the fluorescence change and normalized PL spectra recorded during the solvent-vapor annealing (SVA) process.



**Fig. S5**  $I$ - $V$  characteristics of MIMIC (micro-molding in capillaries)-patterned Py-CN-TFMBE microwires connecting two electrodes separated by a distance of 50  $\mu\text{m}$ . Inset shows an optical microscopy image.